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Electronic Patent Application Submission
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EFS ID: 57385

Application ID: 10698222



Title of Invention: NON-CONTACT METHODS FOR
MEASURING ELECTRICAL
THICKNESS AND DETERMINING
NITROGEN CONTENT OF
INSULATING FILMS

First Named Inventor: Jianou Shi

Domestic/Foreign Application: Domestic Application

Filing Date: 2003-10-31

Effective Receipt Date: 2004-03-18

Submission Type: Information Disclosure
Statement

Filing Type:

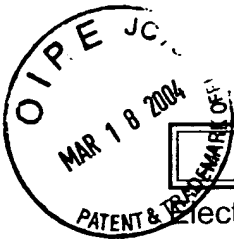
Confirmation number: 1492

Attorney Docket Number: 5589-06800

Total Fees Authorized:

Digital Certificate Holder: cn=Kevin L. Daffer,ou=Registered Attorneys,ou=Patent and Trademark
Office,ou=Department of Commerce,o=U.S. Government,c=US

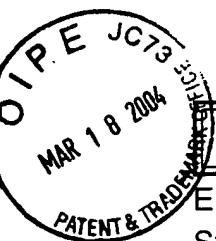
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TRANSMITTAL

Electronic Version v1.1
Stylesheet Version v1.1.0

Title of Invention	NON-CONTACT METHODS FOR MEASURING ELECTRICAL THICKNESS AND DETERMINING NITROGEN CONTENT OF INSULATING FILMS									
Application Number: 10/698222 										
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<table border="1"><thead><tr><th>Submitted by:</th><th>Elec. Sign.</th><th>Sign. Capacity</th></tr></thead><tbody><tr><td>Kevin L. Daffer Registered Number: 34146</td><td>Kevin L. Daffer</td><td>Attorney</td></tr></tbody></table>			Submitted by:	Elec. Sign.	Sign. Capacity	Kevin L. Daffer Registered Number: 34146	Kevin L. Daffer	Attorney		
Submitted by:	Elec. Sign.	Sign. Capacity								
Kevin L. Daffer Registered Number: 34146	Kevin L. Daffer	Attorney								
<table><tr><td>Documents being submitted</td><td>Files</td></tr><tr><td>us-ids</td><td>5589-06800_IDS-usidst.xml</td></tr><tr><td></td><td>us-ids.dtd</td></tr><tr><td></td><td>us-ids.xsl</td></tr></table>			Documents being submitted	Files	us-ids	5589-06800_IDS-usidst.xml		us-ids.dtd		us-ids.xsl
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us-ids	5589-06800_IDS-usidst.xml									
	us-ids.dtd									
	us-ids.xsl									
Comments										



ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of
Invention

NON-CONTACT METHODS FOR MEASURING
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First Named Applicant: Jianou Shi

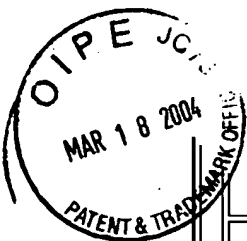
Attorney Docket Number: 5589-06800

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or 4734721 or 5834941 or 6060709 or 6072320
or 6091257 or 6104206 or 6121783 or 6201999
or 6224638 or 20020090746).pn.

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	4015203	1977-03-29	Verkuil			
	2	5767691	1998-06-16	Verkuil			
	3	5485091	1996-01-16	Verkuil			
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	24	3496352	1970-02-17	Jugle
	25	4734721	1988-03-29	Boyer et al.
	26	5834941	1998-11-10	Verkuil
	27	6060709	2000-05-09	Verkuil et al.
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	30	6104206	2000-08-15	Verkuil
	31	6121783	2000-09-19	Horner et al.
	32	6201999	2001-03-13	Jevtic
	33	6224638	2001-05-01	Jevtic et al.

US Published Applications

Note: Applicant is not required to submit a paper copy of cited US Published Applications

init	Cite.No.	Pub. No.	Date	Applicant	Kind	Class	Subclass
	1	20020090746	2002-07-11	Xu et al.			

Signature

Examiner Name	Date